# On the "bendable" ALPIDE-inspired MAPS in 65 nm technology

### Magnus Mager (CERN) on behalf of the ALICE collaboration The 2021 international workshop on the high energy Circular Electron-Positron Collider (CEPC 2021) 8 Nov 2021







# Overview



### Background

- material budget breakdown of detectors (ALICE ITS2)
- thin monolithic sensors
- proposal for ALICE ITS3

### R&D highlights

- bending silicon
- first prototypes in 65 nm technology

### Outlook

towards the wafer-scale sensor





### ALICE LS2 upgrades with Monolithic Active Pixel Sensors (MAPS)





**Inner Tracking System** 

LS2

### 6 layers:

2 hybrid silicon pixel

- 2 silicon drift
- 2 silicon strip

### **Inner-most layer:**

radial distance: 39 mm material:  $X/X_0 = 1.14\%$ pitch:  $50 \times 425 \ \mu m^2$ rate capability: 1 kHz

7 layers: all MAPS 10 m<sup>2</sup>, 24k chips, 12.5 Giga-Pixels

### **Inner-most layer:**

radial distance: 23 mm material:  $X/X_0 = 0.35\%$ pitch:  $29 \times 27 \ \mu m^2$ rate capability: 100 kHz (Pb-Pb)

### **Muon Forward Tracker**

### new detector

5 discs, double sided: based on same technology as ITS2













### Inner Barrel (IB) Flexible PCB 3 Inner Layers: 12+16+20 Staves 9 sensors **1** Module / Stave **Cold Plate 9** sensors per Module Space Frame 96 Modules to be produced (including one spare barrel) **Outer Barrel (OB)** Power Bus Flexible PCB 2 Middle Layers: 30+24 Staves 2×4 Modules / Stave 2 x 7 sensors 2 Outer Layers: 42+48 Staves 2×7 Modules / Stave 2×7 sensors / Module Half-Stave Half-Stave (Middle and Outer Layers are equipped with the same Module

**1880 Modules to be produced** (including spares)











### tarial bu'



### PIXEL PERFECT

A CERN for climate change



# **ITS2** inner barrel



- ITS2 is expected to perform according to specifications or even better
- The Inner Barrel is ultra-light but rather packed  $\rightarrow$  further improvements seem possible
- Key questions: Can we get closer to the IP? Can we reduce the material further?

![](_page_6_Picture_5.jpeg)

### **ITS2:** assembled three inner-most half-layers

![](_page_6_Picture_9.jpeg)

## Material budget a closer look

![](_page_7_Figure_1.jpeg)

- Observations:
  - Si makes only **1/7<sup>th</sup>** of total material
  - irregularities due to support/cooling
- Removal of water cooling
  - **possible** if power consumption stays below 20 mW/cm<sup>2</sup>

![](_page_7_Picture_7.jpeg)

![](_page_7_Figure_8.jpeg)

- Removal of the circuit board (power+data) **possible** if integrated on chip
- Removal of mechanical support
  - **benefit** from increased stiffness by rolling Si wafers

![](_page_7_Picture_13.jpeg)

# **ITS3 performance figures**

### pointing resolution

![](_page_8_Figure_2.jpeg)

[ALICE-PUBLIC-2018-013]

improvement of factor 2 over all momenta

![](_page_8_Picture_6.jpeg)

tracking efficiency

![](_page_8_Figure_8.jpeg)

large improvement for low transverse momenta

![](_page_8_Picture_11.jpeg)

### **Monolithic Active Pixel Sensor** Idea (1): make use of the flexible nature of thin silicon

![](_page_9_Picture_1.jpeg)

![](_page_9_Picture_2.jpeg)

![](_page_9_Picture_3.jpeg)

Silicon Genesis: 20 micron thick wafer

![](_page_9_Picture_4.jpeg)

![](_page_9_Picture_6.jpeg)

![](_page_9_Picture_7.jpeg)

![](_page_9_Picture_8.jpeg)

### **Detector modules** Idea (2): build wafer-scale sensors

![](_page_10_Picture_1.jpeg)

- Chip size is traditionally limited by CMOS manufacturing ("reticle size")
  - typical sizes of few cm<sup>2</sup>
  - modules are tiled with chips connected to a flexible printed circuit board

- New option: stitching, i.e. aligned exposures of a reticle to produce larger circuits
  - actively used in industry
  - a 300 mm wafer can house a sensor to equip a full half-layer

![](_page_10_Picture_10.jpeg)

![](_page_10_Picture_11.jpeg)

- requires dedicated sensor design

![](_page_10_Figure_13.jpeg)

![](_page_10_Picture_15.jpeg)

# R&D (1): bending S

![](_page_11_Picture_1.jpeg)

![](_page_11_Picture_2.jpeg)

["Standard", 50 µm thick ALPIDEs as used for the ITS2 IB, are already quite flexible!]

![](_page_11_Picture_5.jpeg)

![](_page_11_Picture_6.jpeg)

## Bending ALPIDE exampl

tension wire

1100

### 50 µm-thick ALPIDE

out out out out out

foi

### R = 18 mm jig

![](_page_12_Picture_5.jpeg)

### **Beam tests** 1st paper: <u>arxiv:2105.13000</u>

![](_page_13_Figure_1.jpeg)

Fig. 10: Inefficiency as a function of threshold for different rows and incident angles with partially logarithmic scale ( $10^{-1}$  to  $10^{-5}$ ) to show fully efficient rows. Each data point corresponds to at least 8k tracks.

![](_page_13_Picture_4.jpeg)

	- 511	0.0°
	- 447	- 4.9°
•	- 383	- 9.7°
	- 319	- 14.6° <u>එ</u>
	- 255 og	- 19.5° ter
	191	- 24.4° <u>-</u>
	- 127	- 29.2°
	- 63	-34.1°
00	0	39.0°

![](_page_13_Picture_7.jpeg)

### First demonstration of in-beam performance of bent Monolithic Active Pixel Sensors

### **ALICE ITS3**

<sup>a</sup>European Organization for Nuclear Research (CERN), Geneva, Suitzerland <sup>b</sup>GSI. Darmstadt. Germany <sup>e</sup>Heidelberg University, Heidelberg, Cermany <sup>d</sup>INFN & University of Trieste, Trieste, Itoly

### Abstract

A novel approach for designing the next generation of vertex detectors foresees to employ wafer-scale sensors that can be bent to truly cylindrical geometries after thinning them to thicknesses of 20-40 µm. To solidify this concept. the feasibility of operating bent MAPS was demonstrated using  $1.5 \text{ cm} \times 3 \text{ cm}$ ALPIDE chips. Already with their thickness of 50 µm, they can be successfully bent to radii of about 2 cm without any signs of mechanical or electrical damage. During a subsequent characterisation using a 5.4 GeV electron beam, it was further confirmed that they preserve their full electrical functionality as well as particle detection performance.

In this article, the bending procedure and the setup used for characterisation are detailed. Furthermore, the analysis of the beam test, including the measurement of the detection efficiency as a function of beam position and local inclination angle, is discussed. The results show that the sensors maintain their excellent performance after bending to radii of  $2 \,\mathrm{cm}$ , with detection efficiencies above 99.9% at typical operating conditions, paving the way towards a new class of detectors with unprecedented low material budget and ideal geometrical properties.

Keywords: Monolithic Active Pixel Sensors, Solid state detectors, Bent sensors

### 1 1. Introduction

The precision of barrel vertex detectors is mainly determined by three con-

• tributions: their radial distance to the interaction point, their material budget.

a and their intrinsic sensor resolution. In order to achieve hermiticity, they are

typically built out of detector staves placed in layers around the beam pipe. This

arrangement effectively sets a practical limit on the first two factors. ALICE,

\*Corresponding author

Proprint submitted to Nucl. Instrum. Methods Phys. Res. A

February 22, 2021

### Clearly proving that bent MAPS are working!

![](_page_13_Picture_26.jpeg)

### **Beam tests** µITS3

- µITS3, i.e. 6 ALPIDEs at ITS3 radii
  - two complete setups based on "gold" quality **ALPIDE** chips
  - one has a Cu target in the center: expect to see 120 GeV proton/pion–Cu collisions
- Several days of continuous data taking
  - detailed analysis ongoing

![](_page_14_Picture_6.jpeg)

![](_page_14_Picture_10.jpeg)

![](_page_14_Figure_11.jpeg)

### First "real" experiment, allows to study tracking/reconstruction

![](_page_14_Picture_14.jpeg)

# **Beam tests** µITS3

![](_page_15_Figure_1.jpeg)

![](_page_15_Picture_3.jpeg)

### First "real" experiment, allows to study tracking/reconstruction

![](_page_15_Picture_7.jpeg)

![](_page_15_Picture_8.jpeg)

# Bending of wafer-scale sensors procedure

![](_page_16_Picture_1.jpeg)

### 30 mm (L2) 50 µm dummy Silicon

![](_page_16_Picture_4.jpeg)

## Layer assembly

![](_page_17_Picture_1.jpeg)

### **3-layer integration successful!**

![](_page_17_Picture_3.jpeg)

R&D (2): MAPS in 65 nm

![](_page_18_Picture_1.jpeg)

# 65 nm prototypes, MLR1

![](_page_19_Figure_2.jpeg)

![](_page_19_Picture_5.jpeg)

First submission in TowerJazz 65nm

- scoped within CERN EP R&D WP1.2
- significant drive from ITS3
- + important contributions from outside (not ALICE) groups
- Contained several test chips
  - radiation test structures
  - pixel test structures
  - pixel matrices
  - analog building blocks (band gaps, LVDS drivers, etc)

Very versatile first submission, combining what was initially planned for 2 MPWs

![](_page_19_Picture_17.jpeg)

# 65 nm prototypes, MLR1

~12 mm

![](_page_20_Figure_2.jpeg)

16 mm

![](_page_20_Picture_4.jpeg)

- Fully processed wafers are back by now
  - testing has started at many places
- Produced with 4 different process splits
  - TCAD-guided optimisations in collaboration with foundry, comparable to TJ180nm

![](_page_20_Picture_9.jpeg)

![](_page_20_Picture_11.jpeg)

## 65 nm prototypes, MLR1 **Digital Pixel Test Structure (DPTS)**

- Most "aggressive" chip in MLR1
- >  $32 \times 32$  pixels, 15 µm pitch
  - sizeable prototype, allows for "easy" test beam integration
- Asynchronous digital readout with ToT information
- Allows to verify:
  - sensor performance
  - front-end performance
  - basic digital building blocks
  - SEU cross-sections of registers

![](_page_21_Picture_11.jpeg)

![](_page_21_Figure_13.jpeg)

![](_page_21_Picture_15.jpeg)

### **First beam test** Telescope with DPTS

- Scintillator with 1mm hole can be used to trigger on narrow beam spot
- 6 precision linear stages with remote control allow to precisely align 2 DTPS and scintillators

![](_page_22_Picture_3.jpeg)

![](_page_22_Picture_4.jpeg)

scintilator

XY-stage

scintilator

### 3 ALPIDE 2 DPTS 3 ALPIDE

### XY-stage

![](_page_22_Picture_8.jpeg)

![](_page_22_Picture_10.jpeg)

![](_page_22_Picture_11.jpeg)

![](_page_23_Figure_1.jpeg)

first few % of total statistics analysed

![](_page_23_Picture_3.jpeg)

![](_page_23_Picture_4.jpeg)

Beam spot and trigger tuned to illuminate a small area

![](_page_23_Picture_7.jpeg)

![](_page_24_Figure_1.jpeg)

first few % of total statistics analysed

![](_page_24_Picture_3.jpeg)

![](_page_24_Picture_4.jpeg)

### wafer: 22 version: 1 split: 4 (opt.)

- $V_{pwell} = -1.2 V$  $V_{sub} = -1.2 V$  $I_{reset} = 10 \, \text{pA}$  $I_{bias} = 100 \text{ nA}$  $I_{biasn} = 10 \, \mathrm{nA}$  $I_{db} = 100 \, \text{nA}$  $V_{casn} = 300 \,\mathrm{mV}$  $V_{casb} = 250 \,\mathrm{mV}$
- Beam spot and trigger tuned to illuminate a small area
- Looking at tracks without hit in the DPTS, a clear 100% shadow is seen

![](_page_24_Picture_10.jpeg)

![](_page_24_Picture_11.jpeg)

![](_page_25_Figure_1.jpeg)

first few % of total statistics analysed

![](_page_25_Picture_3.jpeg)

![](_page_25_Picture_4.jpeg)

### wafer: 22

- version: 1 split: 4 (opt.)  $V_{pwell} = -1.2 V$  $V_{sub} = -1.2 V$  $I_{reset} = 10 \, pA$  $I_{bias} = 100 \,\mathrm{nA}$  $I_{biasn} = 10 \, \mathrm{nA}$  $I_{db} = 100 \, \text{nA}$  $V_{casn} = 300 \text{ mV}$  $V_{casb} = 250 \text{ mV}$
- Beam spot and trigger tuned to illuminate a small area
- Looking at tracks without hit in the DPTS, a clear 100% shadow is seen
- The area matches precisely the DPTS
- 166/166 tracks in region of interest

![](_page_25_Picture_12.jpeg)

![](_page_26_Figure_1.jpeg)

first few % of total statistics analysed

![](_page_26_Picture_3.jpeg)

![](_page_26_Picture_4.jpeg)

DPTS E wafer: 22 chip: 1 version: X split: 4 (opt.)  $V_{pwell} = -1.2 V$  $V_{sub} = -1.2 V$  $I_{reset} = 10 \, \text{pA}$  $I_{bias} = 100 \,\mathrm{nA}$  $I_{biasn} = 10 \, \mathrm{nA}$  $I_{db} = 100 \, \text{nA}$ 

- Beam spot and trigger tuned to illuminate a small area
- Looking at tracks without hit in the DPTS, a clear 100% shadow is seen
- The area matches precisely the DPTS
- 166/166 tracks in region of interest - similar for second chip (162/162)

![](_page_26_Picture_11.jpeg)

![](_page_27_Figure_1.jpeg)

first few % of total statistics analysed

![](_page_27_Picture_3.jpeg)

![](_page_27_Picture_4.jpeg)

- version: 1 split: 4 (opt.)  $V_{pwell} = -1.2 V$  $V_{sub} = -1.2 V$  $I_{reset} = 10 \, \text{pA}$  $I_{bias} = 100 \text{ nA}$  $I_{biasn} = 10 \, \mathrm{nA}$  $I_{db} = 100 \, \text{nA}$  $V_{casn} = 300 \,\mathrm{mV}$  $V_{casb} = 250 \,\mathrm{mV}$
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- 166/166 tracks in region of interest
  - similar for second chip (162/162)
  - and even for both in coincidence (83/83)

![](_page_27_Picture_15.jpeg)

![](_page_28_Figure_1.jpeg)

![](_page_28_Picture_3.jpeg)

![](_page_28_Picture_4.jpeg)

- version: 1 split: 4 (opt.)  $V_{pwell} = -1.2 V$  $V_{sub} = -1.2 V$  $I_{reset} = 10 \, \text{pA}$  $I_{bias} = 100 \text{ nA}$  $I_{biasn} = 10 \, \mathrm{nA}$  $I_{db} = 100 \, \text{nA}$  $V_{casn} = 300 \,\mathrm{mV}$  $V_{casb} = 250 \,\mathrm{mV}$
- Looking at tracks without hit in the DPTS, a clear 100% shadow is seen

Beam spot and trigger tuned to

illuminate a small area

- The area matches precisely the DPTS
- split: 4 (opt.)  $V_{pwell} = -1.2 V$  $V_{sub} = -1.2 V$  $I_{reset} = 10 \, \text{pA}$  $I_{bias} = 100 \text{ nA}$  $I_{biasn} = 10 \, \mathrm{nA}$
- 166/166 tracks in region of interest
  - similar for second chip (162/162)
  - and even for both in coincidence (83/83)

### Excellent sensor and front-end performance already from first 65 nm prototype

![](_page_28_Picture_15.jpeg)

![](_page_29_Figure_1.jpeg)

Excellent sensor and front-end performance already from first 65 nm prototype

![](_page_29_Picture_3.jpeg)

![](_page_29_Picture_4.jpeg)

Beam spot illuminate a	Beam spot and trigger tuned to illuminate a small area			
Looking at t	racks without hit in the			
)/(162+168) tracks:	ar 100% shadow is se			
%	atches precisely the			
opper-Pearson)	cks in region of interes			
- similar to	r second chip (162/162			
<ul> <li>and even for both in coincidence</li> <li>(83/83)</li> </ul>				
	<ul> <li>Beam spot illuminate a</li> <li>Looking at t</li> <li>/(162+168) tracks:</li> <li>%</li> <li>pper-Pearson)</li> <li>SIMIIar TOI</li> <li>and even (83/83)</li> </ul>			

Magnus Mager (CERN) | bendable MAPS in 65 nm | CEPC 2021 | 08.11.2021 | 21

![](_page_29_Picture_7.jpeg)

en

2

e

![](_page_30_Picture_0.jpeg)

![](_page_30_Picture_1.jpeg)

![](_page_30_Picture_3.jpeg)

### Layer interconnection "super-ALPIDE"

- To study the bending and interconnection of large pieces of processed chips, "super-ALPIDE" is built
  - consists of 1 silicon piece cut from an ALPIDE wafer (9x2 dies, approx 1/2 of layer 0)

![](_page_31_Picture_3.jpeg)

### Layer interconnection (2) "super-ALPIDE"

- A bonding jig is being prepared
- the first row of ALPIDEs will be wire-bonded to an edge-FPC
  - just like the final detector.
- super-ALPIDE/L0 will be held by an exoskeleton that:
  - mimics L1
  - and allows to interconnect all remaining ALPIDE dies

![](_page_32_Picture_7.jpeg)

![](_page_32_Picture_9.jpeg)

### long wires for testing

![](_page_32_Picture_11.jpeg)

### edge bonds (like final ITS3)

![](_page_32_Picture_13.jpeg)

### Key R&D for combining electrical and mechanical prototypes

![](_page_32_Picture_16.jpeg)

![](_page_32_Figure_17.jpeg)

# Summary

- wafer-scale, 20-40 µm-thin, bent MAPS
- R&D on bent MAPS:
  - started with existing, thin MAPS within **ALICE ITS3**
  - in-beam verification of bent MAPS: successful
  - full-size mechanical mockups: build and characterised
- R&D on 65 nm MAPS:
  - joint effort within CERN EP R&D of several groups with large contribution from the ALICE **ITS3** community
  - first submission ("MLR1") came back: >50 prototype chips - detection efficiency of a 32x32 pixel prototype ("DPTS"): **100%**
- for several future vertex detectors

![](_page_33_Picture_11.jpeg)

### ALICE proposes to build the next-generation Inner Tracking System, based on 300 mm-

These newly developed detector technologies have a the potential to be a game changer

![](_page_33_Picture_16.jpeg)

![](_page_34_Picture_0.jpeg)

![](_page_34_Picture_1.jpeg)

![](_page_34_Picture_2.jpeg)

![](_page_34_Picture_4.jpeg)